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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Hajime YAMAMOTO et al.**

Group Art Unit: 1756

Application Number: **10/647,247**

Examiner: **Daborah Chacko Davis**

Filed: **August 26, 2003**

Confirmation Number: 1773

For: **METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE,
AND METHOD OF FORMING RESIST PATTERN**

Attorney Docket Number: **031029**

Customer Number: **38834**

REQUEST FOR WITHDRAWAL OF FINALITY OF OFFICE ACTION

Mail Stop: AF

Commissioner for Patents

P. O. Box 1450

Alexandria, VA 22313-1450

May 16, 2007

Sir:

This paper is filed in response to the Office Action dated April 17, 2007.

Remarks/Arguments begin on page 2 of this paper.